

AMENDMENT TRANSMITTAL LETTER (Large Entity)Applicant(s): **Ju-Cheol SHIN et al.**

Docket No.

SEC.828D

Application No.

10/601,561

Filing Date

June 24, 2003

Examiner

Karla A. Moore

Customer No.

20987

Group Art Unit

1763

Confirmation No.

7739Invention: **CHEMICAL VAPOR DEPOSITION METHOD FOR DEPOSITING SILICIDE AND APPARATUS FOR PERFORMING THE SAME****FEB 08 2005****PATENT & TRADEMARK OFFICE****COMMISSIONER FOR PATENTS:**

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	8 -	20 =	0	x \$50.00	\$0.00
INDEP. CLAIMS	1 -	3 =	0	x \$200.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. _____ in the amount of _____
- ☐ A check in the amount of _____ to cover the filing fee is enclosed.
- ☐ The Director is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account
- ☐ Any additional filing fees required under 37 C.F.R. 1.16.
- ☐ Any patent application processing fees under 37 CFR 1.17.
- ☐ Payment by credit card. Form PTO-2038.

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Stephen R. Whitt
Signature

Dated: **FEBRUARY 8, 2005**

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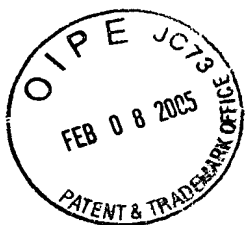
I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to "Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450" [37 CFR 1.8(a)] on

(Date)

Signature of Person Mailing Correspondence

Typed or Printed Name of Person Mailing Correspondence

CC:



Application No. 10/601,561
Attorney Docket No. SEC. 828D
Amendment Filed February 8, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of :

Ju-Cheol Shin et al. : Group Art Unit: 1763

Application No. 10/601,561 : Examiner Karla A. Moore

Filed: June 24, 2003 :

For: CHEMICAL VAPOR DEPOSITION METHOD FOR DEPOSITING SILICIDE AND
APPARATUS FOR PERFORMING THE SAME

AMENDMENT

U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria VA 22314

Sir:

In response to the Office Action of November 9, 2004, please amend the
above-identified application as follows:

Amendments to the Title begin on page 3 of this paper.

Amendments to the Specification begin on page 4 of this paper.

Amendments to the Claims are reflected in the listing of claims which
begins on page 5 of this paper.

Amendments to the Abstract begin on page 7 of this paper.

Remarks/Arguments begin on page 8 of this paper.

Amendments to the Title

Please replace the Title of the Invention with the following new title:

CHEMICAL VAPOR DEPOSITION APPARATUS FOR DEPOSITING
SILICIDE